

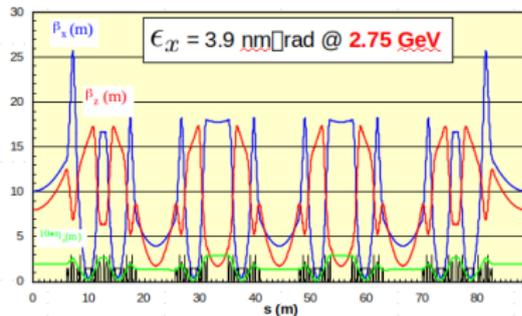
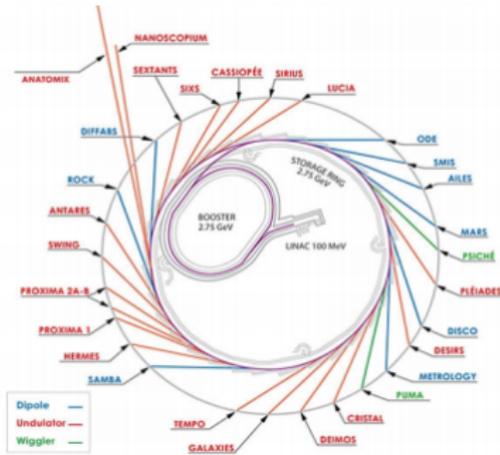


## Optical Diagnostics for SOLEIL–Upgrade

*Transverse beam sizes and emittance measurement*

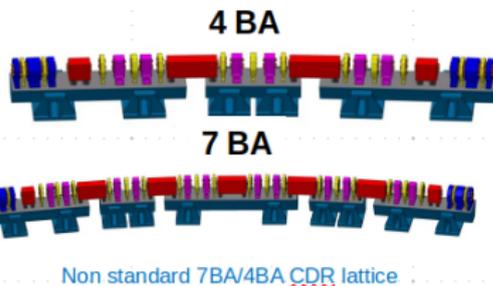
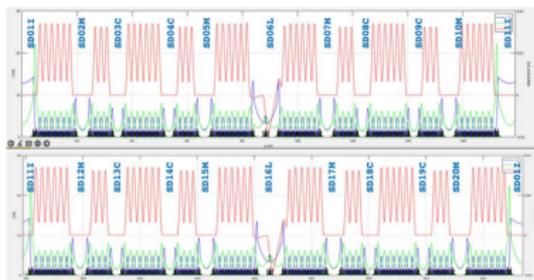
*M. Labat, N. Hubert*

*Workshop @IFAST, April 2022*

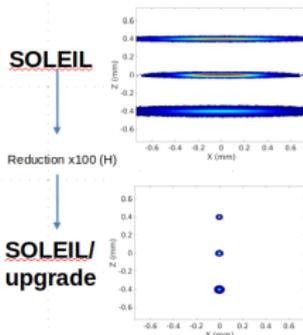


SOLEIL present storage ring

- Storage ring: 354 m circumference
- Lattice: DBA + distributed dispersion
- $\epsilon_x = 3.9 \text{ nm} \cdot \text{rad}$  ;  $\epsilon_y = 40 \text{ pm} \cdot \text{rad}$
- 29 beamlines



SOLEIL–Upgrade lattice



- Lattice: non–standard 7 DBA + 4 DBA
- $\epsilon_x=84.4$  pm.rad ;  $\epsilon_y=25.3$  pm.rad
- Presently in TDR phase...

- Present vs. future parameters:

Machine	SOLEIL	SOLEIL-Upgrade
		Nominal / Machine tuning
$\epsilon_x$ (pm.rad)	4000	84.4 / 90
$\epsilon_y$ (pm.rad)	40	25.3 / 1
$\sigma_x$ in dipoles ( $\mu\text{m-RMS}$ )	45-75	8.3 / 8-17
$\sigma_y$ in dipoles ( $\mu\text{m-RMS}$ )	25	12.5 / 2-3

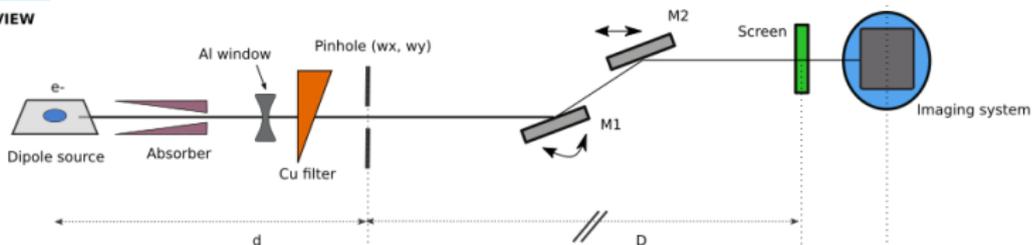
- Specifications for  $\epsilon_{x,y}$  ( $\sigma_{x,y}$ ) measurement:

- $\epsilon_{x,y}$  measurement with sub-pm resolution  
 →  $\sigma_{x,y}$  measurement with sub- $\mu\text{m}$  resolution
- $\epsilon_{x,y}$  (nominal) measurement at  $>100$  Hz repetition rate
- High reliability for  $\epsilon_{x,y}$  (nominal) measurement
- At least 2 measurements of  $\epsilon_{x,y}$  with different  $\eta_{x,y}$

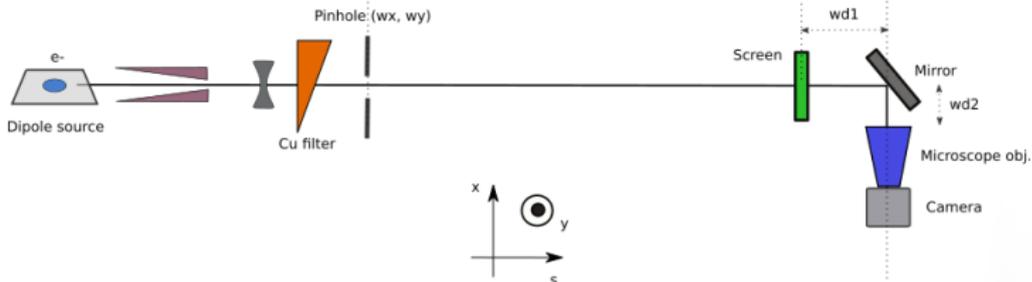
- Development of 2 types of optical diagnostics beamline:
  - X-ray range beamline(s):
    - Based on high-field dipole(s)
    - + Pinhole camera  $\rightarrow \approx 5 \mu\text{m}$ -RMS resolution at  $> 100 \text{ Hz}$   
*(for users' operation)*
    - + Fresnel diffraction  $\rightarrow \approx 1 \mu\text{m}$ -RMS resolution at  $> 10 \text{ Hz}$   
*(for machine tuning)*
  - Near-UV / visible beamline:
    - Based on low-field dipole
    - + Polarized imaging  $\rightarrow \approx 5 \mu\text{m}$ -RMS resolution at  $> 100 \text{ Hz}$   
*(for users' operation)*
    - + Polarized diffraction imaging  $\rightarrow \approx 1 \mu\text{m}$ -RMS resolution at  $> 10 \text{ Hz}$   
*(for machine tuning)*

$\rightarrow$  The beamlines design will ensure to swap from one technique to the other

TOP VIEW

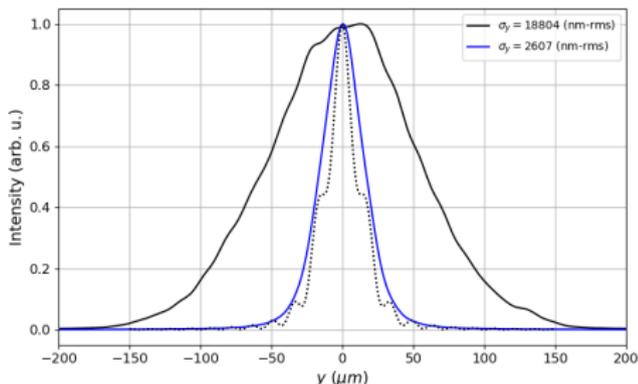


SIDE VIEW



- **Principle:** flip from users' to machine tuning mode removing M1–M2 specular mirrors
- **Main components:**
  - **Easy:** Aluminium window, copper absorber, scintillator, objective
  - **Tricky:** High-field dipole, absorber, adjustable pinhole, specular mirrors, camera

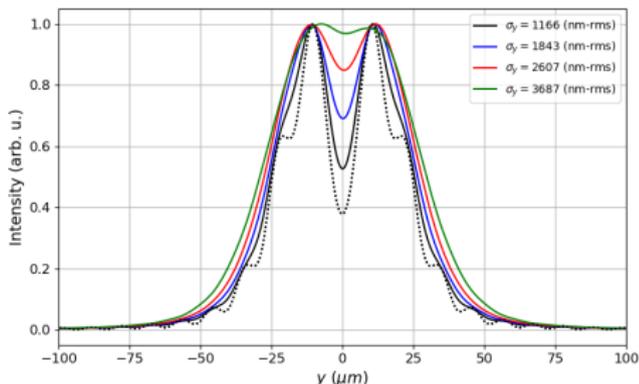
- Expected performances of the pinhole camera ( $E_{phot} > 50$  keV):



$B=3$  T,  $d=3$  m,  $M_W=2.66$ ,  $E_V=50$  keV,  $w_y=14$   $\mu\text{m}$

→ Should resolve down to  $\sigma_{x,y} \approx 5$   $\mu\text{m}$ -RMS

- Expected performances of Fresnel diffraction ( $E_{phot} > 50$  keV):



$B=3$  T,  $d=3$  m,  $M_W=2.66$ ,  $E_V=50$  keV,  $w_y=19$   $\mu\text{m}$

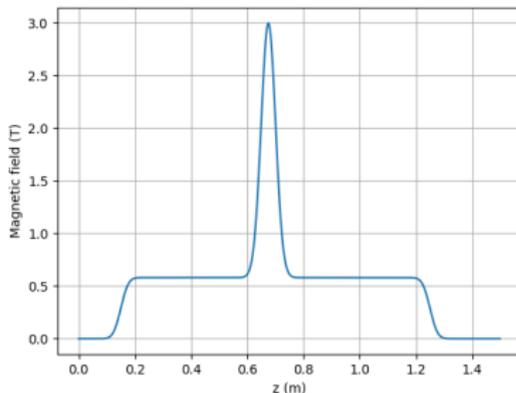
→ Should resolve down to  $\sigma_{x,y} \approx 1$   $\mu\text{m}$ -RMS

- Expected performances in the X-ray range ( $E_{phot} > 50$  keV):
  - The dipole field has little influence on ultimate resolution
  - BUT... a strong impact on **photon flux !!!**
    - For **100 Hz** (?) repetition rate →  **$B=3$  T** mandatory.



- Source dipole:

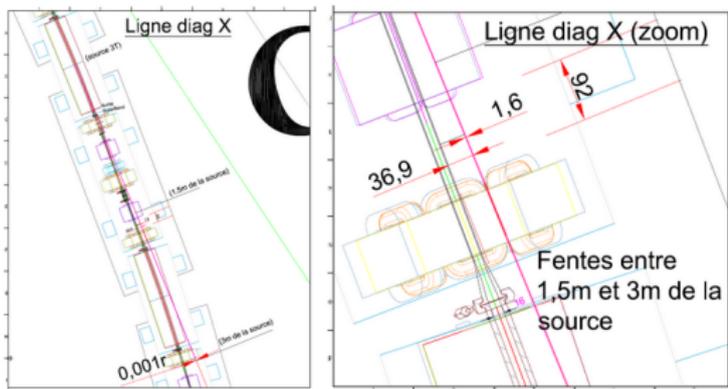
- To enable 100 Hz measurements @  $E_{phot} > 50$  keV  $\rightarrow B > 2.5$  T
- Target: use one of the *long* dipoles with central field @  $B=3$  T



Long dipole longitudinal magnetic field with central field @ 3 T. Courtesy A. Loulergue. PRELIMINAR DESIGN.

- Beamline(s) integration:

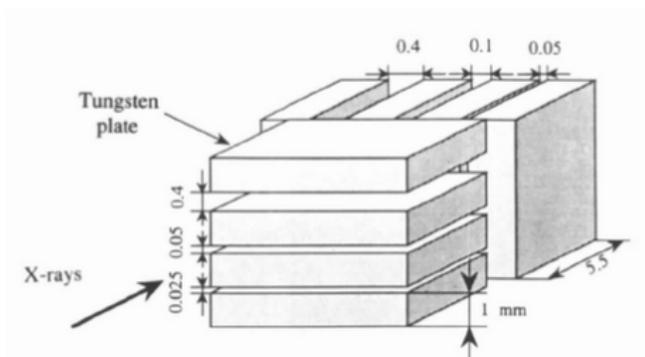
- Source dipole = long + free dipole
- To enable high resolution:  $M > 2.5 \rightarrow d_{source-pinhole} < 3 \text{ m}$



Integration of X-ray beamline on a 3 T long dipole. PRELIMINAR DESIGN.

- So: pinhole will still be *in between* DBA magnets.... = tiny space !

- Pinhole design: (1) Stacking of blades + shims

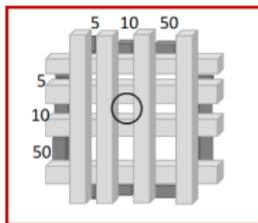


Pinhole design from P. Elleaume et al., J. Synchrotron Rad. (1995) 2, 209-214.

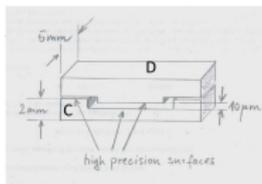
- **Pros:** Proven, compact, cheap, reliable
- **Cons:** Fixed set of hole sizes, no or non-accurate metrology, painful assembly

→ Alternative ?

- Pinhole design: (2) Alternatives investigated
  - LIGA >> no. Not enough attenuation power.
  - Motorized micro-slits >> no. Too expensive, not reliable enough.
  - Other mechanical design based on ESRF / ALBA experience >> yes.



*New "CD shaped" pinhole design*

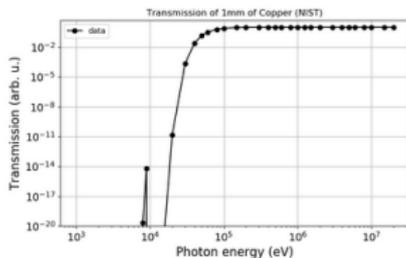


Pinhole model from ALBA and ESRF. Courtesy U. Iriso and F. Ewald.

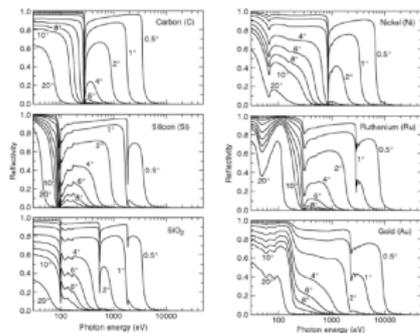
→ Study of a new mechanical design to be soon started

## X-ray beamline(s) &gt;&gt; Main components

- Monochromator (for Fresnel diffraction ONLY): just an idea...
  - Statements:
    - We only need **XX** linewidth to reach 1  $\mu\text{m}$  resolution in Fresnel diffraction
    - No need to implement **XX** linewidth standard monochromator: it will kill flux: see Diamond and ESRF....
  - Alternative idea: make a **band-pass filter** ?
    - High-pass filter = Copper attenuator
    - Low-pass filter = Pair of mirrors in specular reflection



Copper transmission = High-pass filter



Specular mirror reflectivity = Low-pass filter

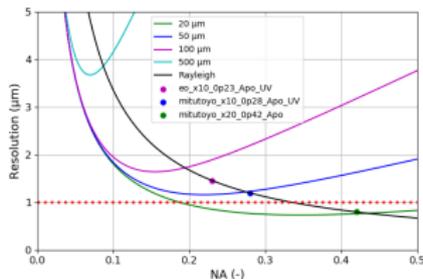
- Many critical issues still: x offset ? final flux ? alignment ?  $X_{\text{camera}}$  ?

## ● Scintillator:

## ● Specifications:

- Short time response (<0.1 ms)
- Spatial resolution <1  $\mu\text{m}$
- High yield
- Emission around 500 nm to match camera efficiency
- Linear response
- Thickness = compromise output yield / resolution decrease from d.o.f.  
→ between 0.02 and 0.1  $\mu\text{m}$

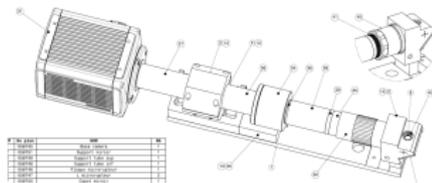
→ CdW04, Yag:Ce, LuAg:Ce, GaGG



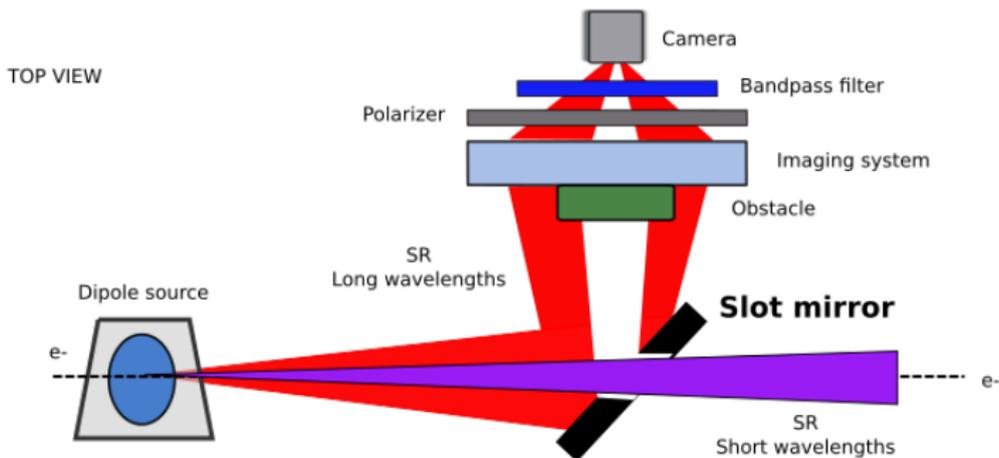
Resolution versus Numerical Aperture for different scintillator thickness.

- Imaging system:

- Compact + stable mechanics  
from Detetor Group design  
*(housing: scintillator + mirror + objective + camera + focus stage)*
- Objective = microscope  
*(EdmundOptics + Mitutoyo to be tested)*
- Camera = ?  
*(not defined yet)*

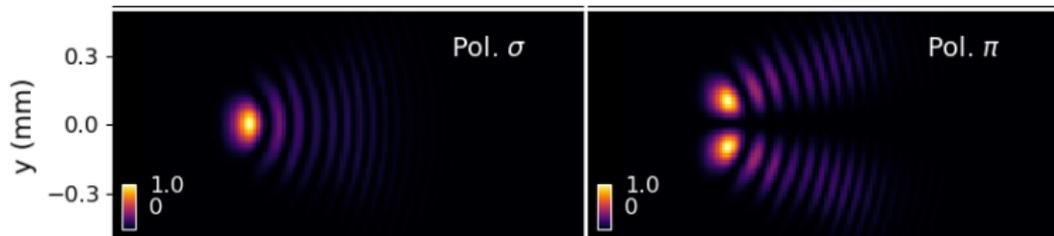


X-ray beam imager prototype.



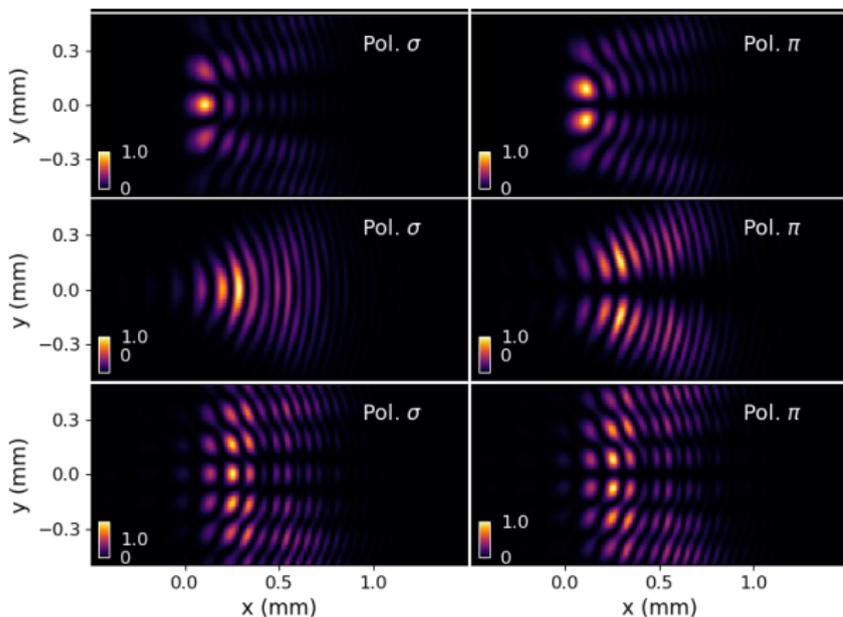
- **Principle:** flip from users' to machine tuning mode adding an obstacle
- **Main components:**
  - **Easy:** Low-field dipole, thin obstacle, focussing lens, polarizer, objective
  - **Tricky:** Extraction mirror, camera

- Expected performances of the polarized imaging (@ $\lambda=200$  nm):



→ Should resolve down to  $\sigma_{x,y} \approx 5 \mu\text{m-RMS}$

- Expected performances of the obstacle + polarized imaging (@ $\lambda=200$  nm):



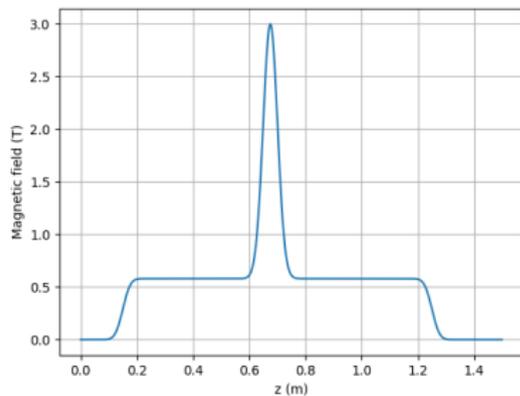
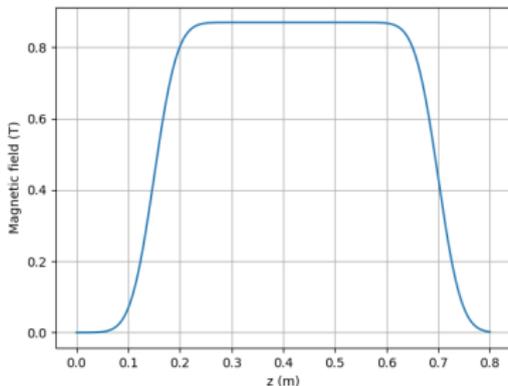
→ Should resolve down to  $\sigma_{x,y} \approx 2 \mu\text{m-RMS}$  → to be more optimized...

- Expected performances in near-UV / visible range (down to 200 nm):
  - Since we'll work with large  $\theta_x$ :
    - $B$  longitudinal distribution will be important (flat / not)
  - The lower the field... the higher the photon flux
    - For 100 Hz (?) repetition rate →  $B < 1.7$  T mandatory



- Source dipole:

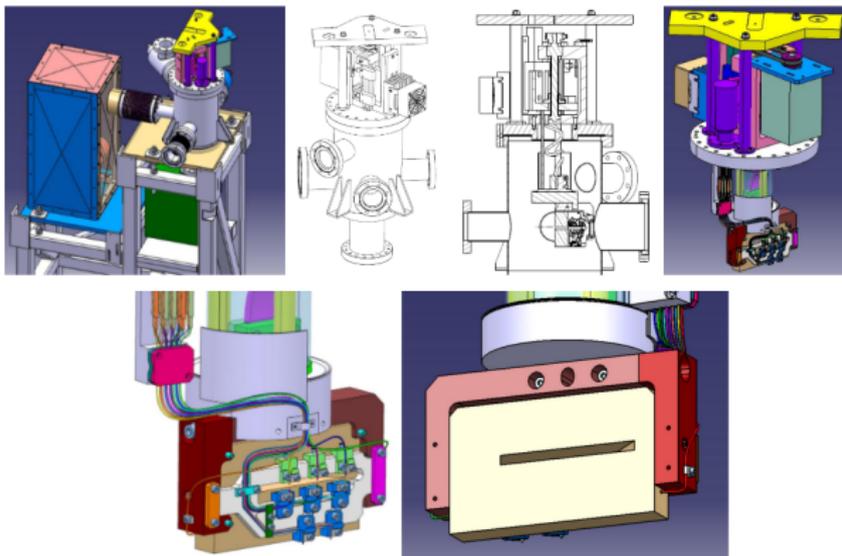
- To enable 100 Hz measurements @  $200 \text{ nm} < \lambda < 1 \mu\text{m} \rightarrow B < 1.7 \text{ T}$
- Target: use one of the *short* dipoles @  $B=0.87 \text{ T}$ ,  
or first/last part of a *long* dipole @  $B=0.58 \text{ T}$



Short and long dipole longitudinal magnetic field. Courtesy A. Louergue. PRELIMINAR DESIGN.

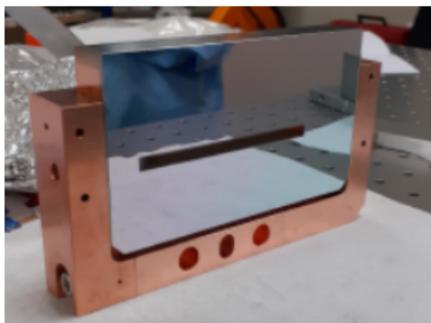
- Extraction mirror:

- Principle: Slotted mirror + air-cooling system
- To test high resolution polarized imaging with such system:



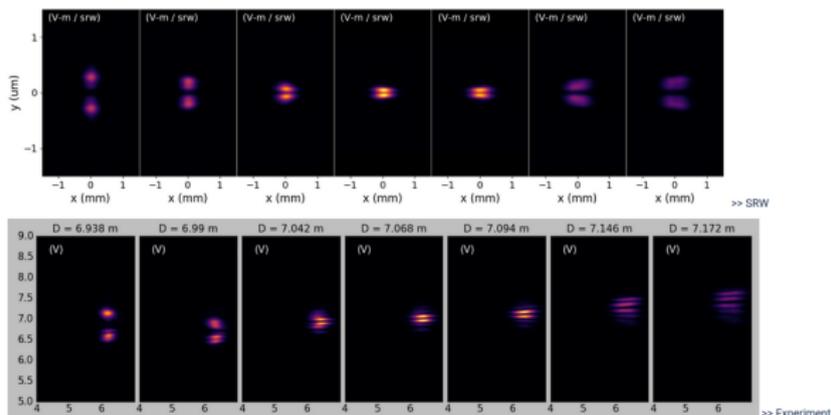
→ Installation in January 2022 of a new extraction mirror on our visible beamline

- Preliminar results with our new extraction mirror:
  - Mirror performances:
    - Mirror made of Copper + enhanced Alumium deposition
    - Very high surface quality even around the slot !!  
(flatness < 250 nm PV, roughness < 3 nm-rms)
    - Excellent thermal stability up to 500 mA stored: no image distorsion !!



→ High quality mirrors are feasible on copper :-)

- Preliminary results with our new extraction mirror:
  - Images measured and simulated vs. distance lens-camera (pol. V):

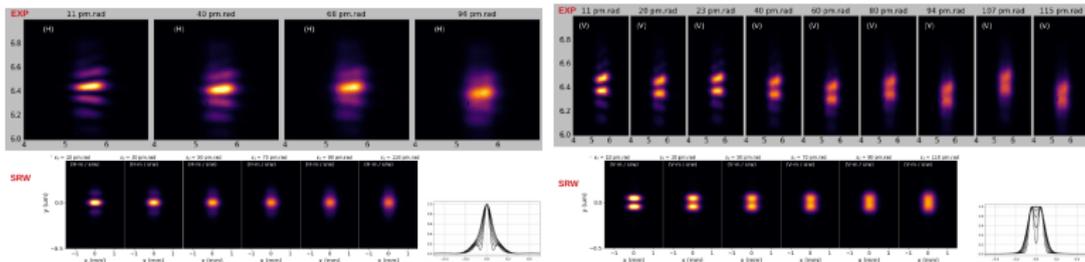


Images vs distance to lens.  $\theta_x=3.5$  mrad, Pol. V.

→ Good agreement “by eye” SRW / measurements :-)

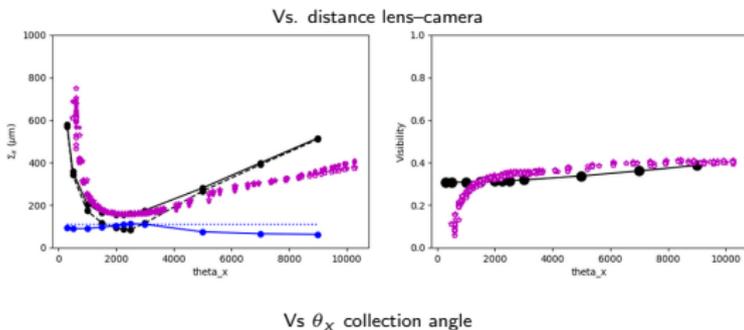
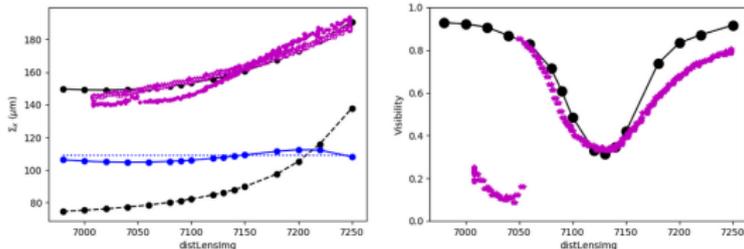


- Preliminary results with our new extraction mirror:
  - Images measured and simulated vs.  $\epsilon_y$ :



→ Sensitivity “by-eye” seems very good in both  $\sigma/\pi$  pol. :-)

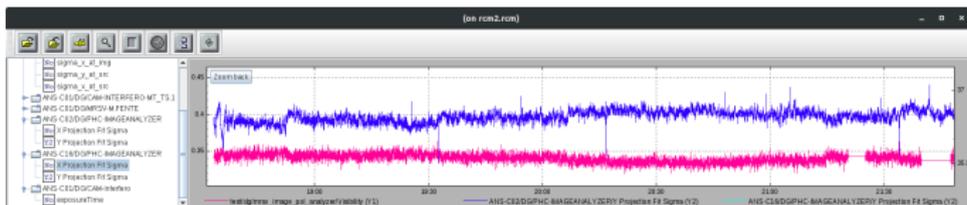
- Preliminary results with our new extraction mirror:
  - Horizontal beam size  $\Sigma_x$  and Visibility in image plane (pol. V):



Experiment / SRW with:  $d=5940$  mm,  $f_x=3200$ mm,  $f_y=3240$  mm

→ Quite good absolute agreement SRW / measurements... but to be improved

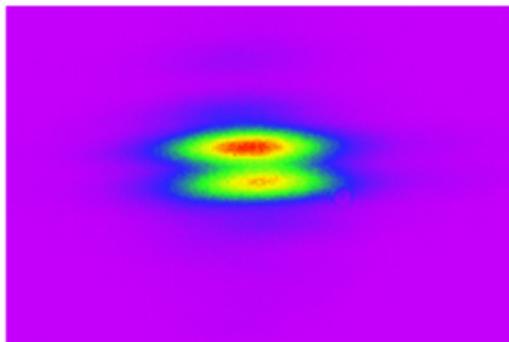
- Preliminary results with our new extraction mirror:
  - Sensitivity Visibility vs.  $\epsilon_y$  from Pinhole Cameras:



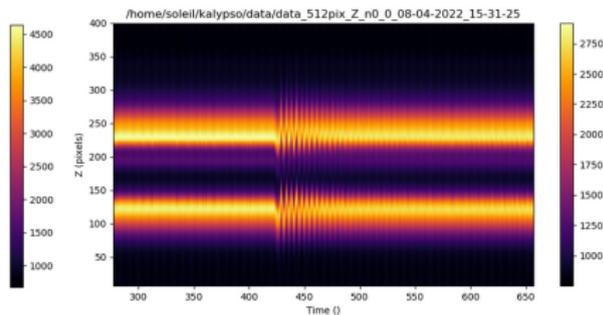
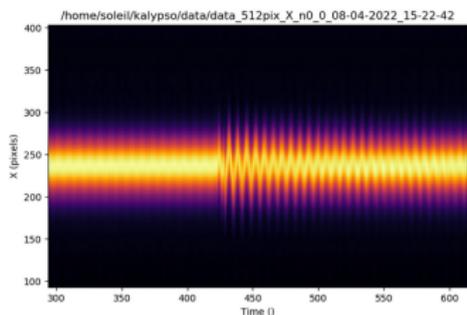
→ Good sensitivity in pol. V seems confirmed.



- Preliminar results with our new extraction mirror: TO BE DONE
  - Check experimental magnification with bumps at source point
  - Check vertical alignment of mirror
  - Improve beamline stability ( $N_2$  or vacuum transport)
  - Improve periscope alignment
  - Improve SRW/measurment agreement



- Other development on our present visible beamline: ultra-fast imaging
  - Kalypso (KIT) camera implemented on  $\sigma$  pol. branch
  - Ultra-fast acquisition (up to 3 MHz)  $\rightarrow$  turn-by-turn (846 kHz) imaging
  - Allows to follow injection effect on stored beam for instance

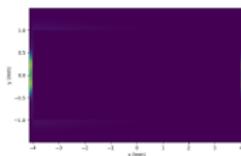
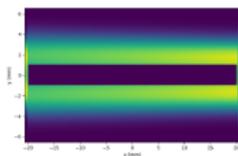
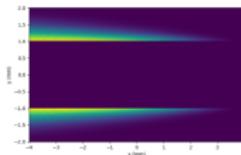
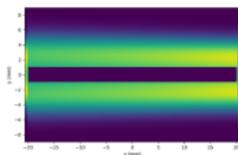


- Even if not yet absolute beam size measurement...

$\rightarrow$  Very useful for recent commissioning of MIK (to be published)



- Extraction mirror: back to SOLEIL–Upgrade topic...
  - For machine operation  $\rightarrow$  slot height  $> 2$  mm
  - For large  $\theta_x$  measurements  $\rightarrow \theta_x > 20$  mrad
  - For photon collection down to 200 nm  $\rightarrow d_{source-mirror} > 3$  m
  - But deposited power rapidly increases with  $d_{source-mirror} \dots$
  - And power density slowly decreases with  $d_{source-mirror} \dots$

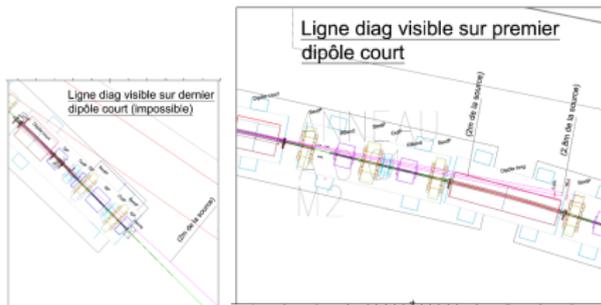
(a)  $D=400$  mm,  $\lambda=200$  nm.(b)  $D=2000$  mm,  $\lambda=200$  nm.(c)  $D=400$  mm,  $\lambda=500$  nm.(d)  $D=2000$  mm,  $\lambda=500$  nm.

Intensity distribution at 200 and 500 nm at 0.4 and 2 m from source point.  $\theta_x=20$  mrad,  $\theta_x=10$  mrad.

$\rightarrow$  Extraction mirror design IS an issue... working on it...

- Beamline(s) integration:

- Source dipole = short + free dipole
- To enable large collection angle + limited power deposition on mirror:
  - extraction at  $d > 2$  m from source point.... with *free path*....



Integration of near-UV / visible beamline on short dipole. PRELIMINAR DESIGN.

→ Beamline integration IS ALSO an issue... working on it...

- Other components:

- Transport mirrors, lenses, polarizer, bandpass filters, etc....  
→ should be easy...
- Fast computation of beam size (100 Hz):  
→ could be more tricky... → to be tested on our visible beamline

→ A lot of preliminar work can be done on our visible beamline



- For  $\epsilon_{x,y}$  ( $\sigma_{x,y}$ ) measurements:
    - Pinhole + Fresnel diffraction in the X-ray range
    - Polarized + obstacle imaging in the near-UV/visible range
  
  - **Announcement: two post-doc positions opened at SOLEIL**
    - Beam diagnostics for the new booster  
<https://www.synchrotron-soleil.fr/en/job-offers/post-doctoral-position-boosters-diagnostics>
    - Photon BPMs for the new storage ring front-ends  
<https://www.synchrotron-soleil.fr/en/job-offers/post-doctorat-photon-bpm>
- to work on diagnostics for SOLEIL-Upgrade

